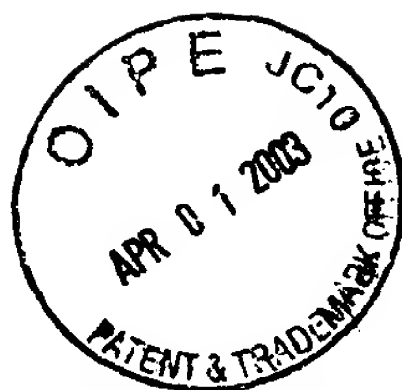


1201.65872



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: )

Applicant: Bohn et al. )

Serial No.: 09/989,050 )

Filed: November 20, 2001 )

For: METAL ASSISTED CHEMICAL )  
ETCH TO PRODUCE POROUS )  
GROUP III-V MATERIALS )

Art Unit: 1746 )

Examiner: Unassigned )

I hereby certify that this paper is being deposited with  
the United States Postal Service as FIRST-CLASS mail  
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March 27, 2003

Date  
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Appr. February 20, 1998

Chris B. R.   
Registration No. 43,874

Attorney for Applicant

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

In accordance with 37 C.F.R. §§1.56, 1.97 and 1.98, Applicants through counsel  
herewith:

Submit copies of patents and publications as set forth in the attached form PTO-  
1449 as follows.

UNITED STATES PATENTS

<u>Patent No.</u>	<u>Issued</u>	<u>Patentee(s)</u>
3,653,989	Apr. 4, 1972	Widmer
4,078,945	Mar. 14, 1978	Gonsiorawski

4,681,657	Jul. 21, 1987	Hwang et al.
5,089,293	Feb. 18, 1992	Bohara et al.
5,695,557	Dec. 9, 1997	Yamagata et al.
5,868,947	Feb. 9, 1999	Sakaguchi et al.
5,873,003	Feb. 16, 1999	Inoue et al.
5,895,223	Apr. 20, 1999	Peng et al.
5,981,400	Nov. 9, 1999	Lo
5,990,605	Nov. 23, 1999	Yoshikawa et al.
6,017,811	Jan. 25, 2000	Winton et al.
6,093,941	Jul. 25, 2000	Russell et al.

#### **OTHER DOCUMENTS**

1. D. Dimova-Malinovska, M. Sendova-Vassileva, N. Tzenov and M. Kamenova, "Preparation of Thin Porous Silicon Layers by Stain Etching", *Thin Solid Films*, 297, 1997, pp. 9-12.

#### **REMARKS**

A number of the references included herein were cited in communications from a foreign office (copies enclosed). Because this Information Disclosure Statement is believed to be filed before the mailing of a first Office Action on the merits, no fee is believed to be due. However, the Commissioner is hereby authorized to charge any

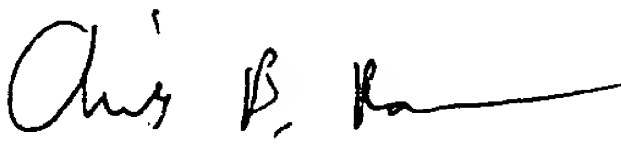
necessary fees under 37 C.F.R. §1.17(p) to Deposit Account No. 07-2069 to allow considerations of these references.

Applicants respectfully request that the Examiner consider the above-listed references in the examination of this application and list these references of record in the application.

The Commissioner is hereby authorized to charge any additional fees which may be required in this application under 37 CFR §§1.16-1.17, or credit any overpayment, to Deposit Account No. 07-2069. A duplicate copy of this sheet is attached.

Respectfully submitted,

GREER, BURNS & CRAIN, LTD.

By 

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Form PTO-1449 U.S. Department of Commerce  
(Rev. 8-88) Patent and Trademark Office

Attorney Docket No.: 1201.65872

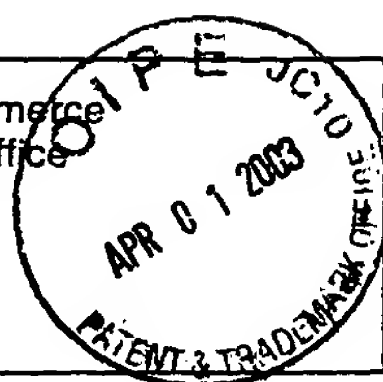
Serial No.: 09/989,050

INFORMATION DISCLOSURE CITATION  
(Use several sheets if necessary)

Applicant: Bohn et al.

Filing Date: Nov. 20, 2001

Group: 1746



## U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	3,653,989	Apr. 4, 1972	Widmer			
	4,078,945	Mar. 14, 1978	Gonsiorawski			
	4,681,657	Jul. 21, 1987	Hwang et al.			
	5,089,293	Feb. 18, 1992	Bohara et al.			
	5,695,557	Dec. 9, 1997	Yamagata et al.			
	5,868,947	Feb. 9, 1999	Sakaguchi et al.			
	5,873,003	Feb. 16, 1999	Inoue et al.			
	5,895,223	Apr. 20, 1999	Peng et al.			
	5,981,400	Nov. 9, 1999	Lo			
	5,990,605	Nov. 23, 1999	Yoshikawa et al.			
	6,017,811	Jan. 25, 2000	Winton et al.			
	6,093,941	Jul. 25, 2000	Russell et al.			

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## FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

D. Dimova-Malinovska, M. Sendova-Vassileva, N. Tzenov and M. Kamenova, "Preparation of Thin Porous Silicon Layers by Stain Etching", *Thin Solid Films*, 297, 1997, pp. 9-12.

Examiner

Date Considered